

Pamela Dunston at least seven days prior to the meeting at 202-376-8105. TDD: (202) 376-8116.

Dated: August 17, 2010.

David Blackwood,
General Counsel.

[FR Doc. 2010-20752 Filed 8-17-10; 4:15 pm]

BILLING CODE 6335-01-P

DEPARTMENT OF COMMERCE

International Trade Administration

Application(s) for Duty-Free Entry of Scientific Instruments

Pursuant to Section 6(c) of the Educational, Scientific and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, as amended by Pub. L. 106-36; 80 Stat. 897; 15 CFR part 301), we invite comments on the question of whether instruments of equivalent scientific value, for the purposes for which the instruments shown below are intended to be used, are being manufactured in the United States.

Comments must comply with 15 CFR 301.5(a)(3) and (4) of the regulations and be postmarked on or before September 8, 2010. Address written comments to Statutory Import Programs Staff, Room 3720, U.S. Department of Commerce, Washington, DC 20230. Applications may be examined between 8:30 a.m. and 5 p.m. at the U.S. Department of Commerce in Room 3720.

Docket Number: 10-052. **Applicant:** Argonne National Laboratory, UChicago Argonne, LLC, 9700 South Cass Avenue, Lemont, IL 60439. **Instrument:** Pilatus 2M Pixel Detector System.

Manufacturer: Dectris Ltd., Switzerland. **Intended Use:** The instrument will be used to obtain fine structural information for materials during chemical reactions, such as catalysis. The instrument has gatable data processing as well as high time resolution and high spatial resolution, which makes the instrument unique. Other unique features include direct detection of x-rays in single-photon-counting mode, a radiation-tolerant design, a high dynamic range, a short readout time, high frame rates, high counting rates, and shutterless operation. **Justification for Duty-Free Entry:** There are no instruments of the same general category being manufactured in the United States.

Application accepted by Commissioner of Customs: July 23, 2010.

Docket Number: 10-053. **Applicant:** Argonne National Laboratory, UChicago Argonne, LLC, 9700 South Cass Avenue, Lemont, IL 60439. **Instrument:** UHV low-Temperature Atomic Force

Microscope System for Application in High Magnetic Fields. **Manufacturer:** Omicron Nanotechnology, Germany. **Intended Use:** The instrument will be used to study atomic scale electrical and magnetic properties of electrically conduction as well as insulation nanostructures prepared by in situ deposition onto clean surfaces. In-situ capacities allow the preparation of clean and well-defined nanostructures on pristine surfaces which would contaminate otherwise. Unique features of this instrument include the capability of applying large magnetic fields (≤ 3 Tesla), which is necessary to allow the clear separation of structural, electronic, and magnetic signals of nanostructures and the evaluation of the properties to be studied in these experiments. The instrument also has in-situ preparation capability and the ability to operate in low temperatures. Further, the instrument is capable of performing imaging in two main modes of operation, i.e., scanning tunneling microscopy and atomic force microscopy. **Justification for Duty-Free Entry:** There are no instruments of the same general category being manufactured in the United States. **Application accepted by Commissioner of Customs:** July 21, 2010.

Dated: August 11, 2010.

Christopher Cassel,

Director, IA Subsidies Enforcement Office.

[FR Doc. 2010-20613 Filed 8-18-10; 8:45 am]

BILLING CODE 3510-DS-P

DEPARTMENT OF COMMERCE

International Trade Administration

University of Massachusetts Amherst, et al.; Notice of Consolidated Decision on Applications for Duty-Free Entry of Electron Microscopes

This is a decision consolidated pursuant to Section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, as amended by Public Law 106-36; 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5 p.m. in Room 3720, U.S. Department of Commerce, 14th and Constitution Avenue., NW., Washington, DC.

Docket Number: 10-044. **Applicant:** University of Massachusetts Amherst, Amherst, MA 01003. **Instrument:** Electron Microscope. **Manufacturer:** FEI Company, Czech Republic. **Intended Use:** See notice at 75 FR 42377, July 21, 2010.

Docket Number: 10-047. **Applicant:** Appalachian State University, Boone, NC 28608. **Instrument:** Electron Microscope.

Manufacturer: JEOL, Ltd., Japan.

Intended Use: See notice at 75 FR 42377, July 21, 2010.

Docket Number: 10-048. **Applicant:** The University of Texas at El Paso, El Paso, TX 79968. **Instrument:** Electron Microscope. **Manufacturer:** JEOL, Ltd., Japan. **Intended Use:** See notice at 75 FR 42377, July 21, 2010.

Docket Number: 10-050. **Applicant:** Stanford University School of Medicine, Stanford, CA 94305-5301. **Instrument:** Electron Microscope. **Manufacturer:** JEOL, Ltd., Japan. **Intended Use:** See notice at 75 FR 42377, July 21, 2010.

Comments: None received. **Decision:** Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as these instruments are intended to be used, was being manufactured in the United States at the time the instruments were ordered. **Reasons:** Each foreign instrument is an electron microscope and is intended for research or scientific educational uses requiring an electron microscope. We know of no electron microscope, or any other instrument suited to these purposes, which was being manufactured in the United States at the time of order of each instrument.

Dated: August 12, 2010.

Christopher Cassel,

Director, Subsidies Enforcement Office, Import Administration.

[FR Doc. 2010-20616 Filed 8-18-10; 8:45 am]

BILLING CODE 3510-DS-P

DEPARTMENT OF COMMERCE

Bureau of the Census

Census Scientific Advisory Committee; Notice of Public Meeting

AGENCY: Bureau of the Census, Department of Commerce.

ACTION: Notice of public meeting.

SUMMARY: The Bureau of the Census (U.S. Census Bureau) is giving notice of a meeting of the Census Scientific Advisory Committee (C-SAC). The Committee will address policy, research, and technical issues relating to a full range of Census Bureau programs and activities, including communications, decennial, demographic, economic, field operations, geographic, information technology, and statistics. Last minute changes to the agenda are possible, which could prevent giving advance public notice of schedule adjustments.